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Title	Study on IEC with magnetic field at Tokyo Institute of Technology
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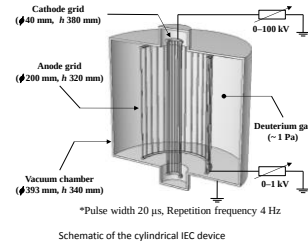
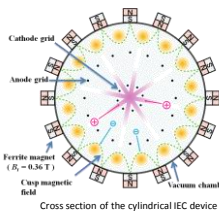
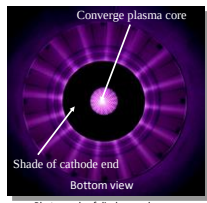
Cylindrical IEC device with axial cusp magnetic field

To reduce pressure

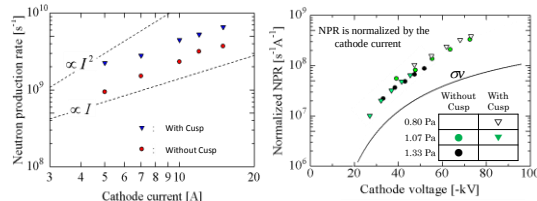
The axial cusp magnetic field confined electrons near the chamber wall and ions were produced and accelerated efficiently in a low pressure operation.

To increase cathode current

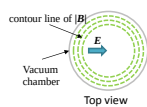
The high current pulsed operation was attempted.



✓ The pressure, cathode voltage and current can not be controlled independently.



- Beam-cathode, beam-background reaction were dominant.
- The cusp magnetic field and the anode biasing were effective to enhance the NPR.
- The maximum NPR was $7.4 \times 10^3 \text{ s}^{-1}$ ($V_c = -80 \text{ kV}$, $I_c = 15 \text{ A}$)
- As the pressure decreased, the normalized NPR became high.



The confinement effect of the axial cusp magnetic field was not sufficient, because electrons moved in the axial direction by $\mathbf{E} \times \mathbf{B}$ drift motion.

The ways to improve NPR

◆ To increase ion density

- To increase cathode current
- To improve ion confinement

with cusp

MEC

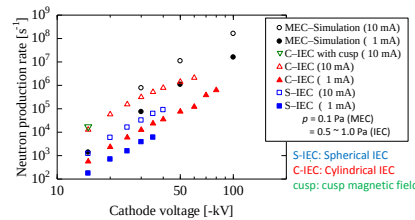
◆ To increase ion energy

- To reduce pressure
- To increase cathode voltage

with cusp

MEC

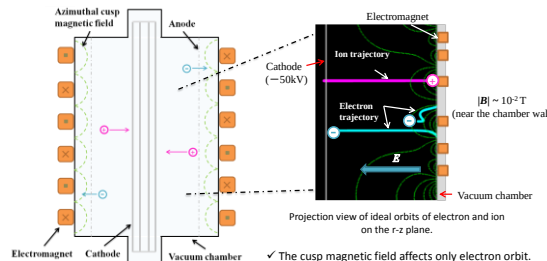
Comparison of NPR



- The MEC device has similar performance to that of the cylindrical IEC device with axial cusp magnetic field.
- The expected NPR of the MEC device: $1.6 \times 10^8 \text{ s}^{-1}$ ($V_c = -100 \text{ kV}$, $I_c = 10 \text{ mA}$, $B_z = 240 \text{ mT}$)

New trial Azimuthal cusp magnetic field

Azimuthal cusp magnetic field is expected to confine electrons and produce ions more effectively at low pressure, because electrons move in the azimuthal direction by $\mathbf{E} \times \mathbf{B}$.



✓ The cusp magnetic field affects only electron orbit.

References

1. Tomiyasu et al., "Particle-in-cell simulation of magnetic-assisted electrostatic confinement device," Fusion Engineering and Design, Elsevier, Vol. 85, pp. 728-733 (2010).
2. K. Tomiyasu et al., "EFFECTS OF CUSP MAGNETIC FIELD IN A CYLINDRICAL RADIALLY CONVERGENT BEAM FUSION DEVICE," Fusion Science and Technology, Vol. 56, pp. 967-971 (2009).
3. K. Yamauchi et al., "Performance of Neutron/Proton Source Based on Ion-Source Assisted Cylindrical Radially Convergent Beam Fusion," IEEE Trans. Nucl. Sci., Vol. 56, No. 1, pp. 117-122 (2009).

MEC

(Magnetic-assisted Electrostatic Confinement)

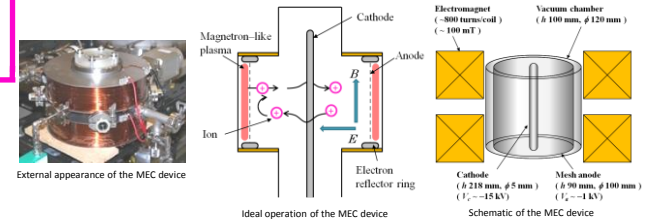
To increase ion density in a low pressure and low current operation

To improve ion confinement

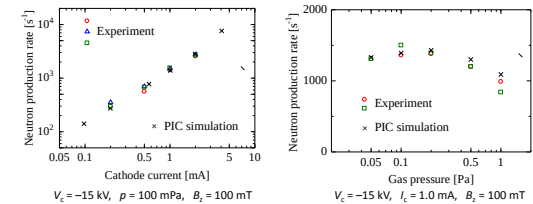
An axial uniform magnetic field was applied to prevent ions from hitting the central cathode rod.

Ion source-assisted operation

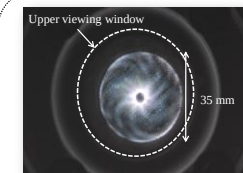
The magnetron motion and electron reflector rings confined electrons near the anode and enhanced ion generation was expected at low pressure. Production of a localized plasma was suppressed near the cathode.



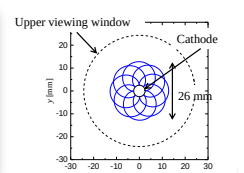
✓ The pressure, voltage and current can be controlled independently.



- The maximum NPR was $2.6 \times 10^3 \text{ s}^{-1}$ ($V_c = -15 \text{ kV}$, $I_c = 2 \text{ mA}$)
- The cathode current was limited by the space charge limitation. ($V_c = -15 \text{ kV} \Rightarrow I_c < 4 \text{ mA}$)
- Beam-cathode reaction was a dominant fusion type, assuming the deuterium density in the electrodes $3 \times 10^{23} \text{ m}^{-3}$ in the PIC simulation.



Luminous region at the upper viewing window ($V_c = -15 \text{ kV}$, $I_c = 1 \text{ mA}$, $p = 100 \text{ mPa}$, $B_z = 50 \text{ mT}$)



Orbit of secondary electron from cathode

Ion generation occurred near the cathode, because a lot of secondary electrons were trapped around the cathode by the uniform magnetic field.